

# LGAD sensors & plans for a beam telescope timing layer

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DESY SiDet R&D meeting



Universität Hamburg  
DER FORSCHUNG | DER LEHRE | DER BILDUNG



**CLUSTER OF EXCELLENCE**  
QUANTUM UNIVERSE

# The need for new timing detectors

Experimental environments are evolving

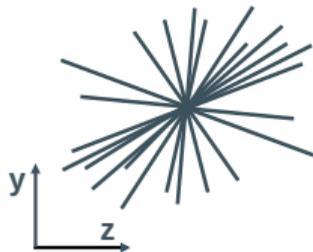
→ Include track timing to address new challenging conditions

Time information complements spatial information:

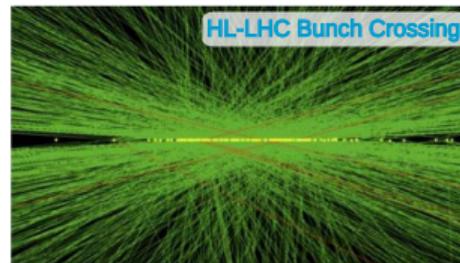
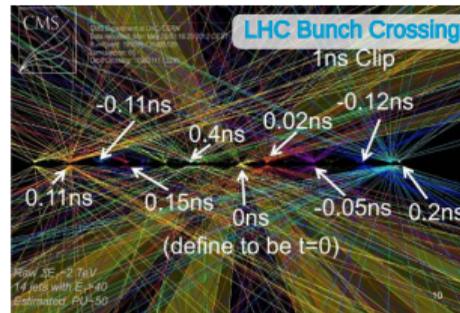
- ▶ **Timing layer:** timing in event reconstruction
- ▶ “4D” tracking: timing at each point along the track

Example goals/requirements: HL-LHC 50 ps, HADES 60 ps, FCC-hh 10 ps

## Example



pileup tracks



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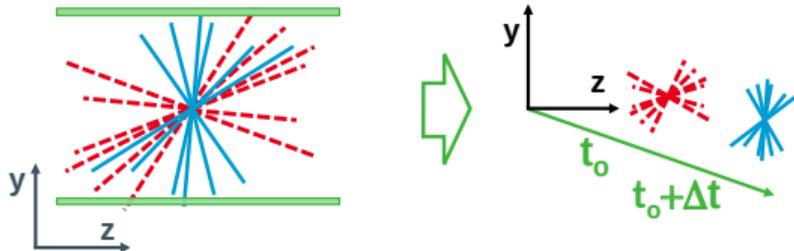
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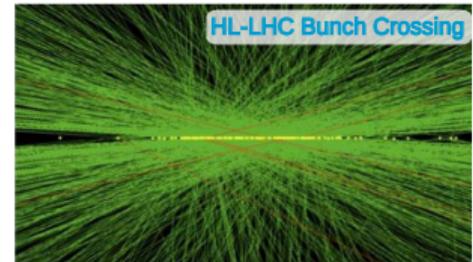
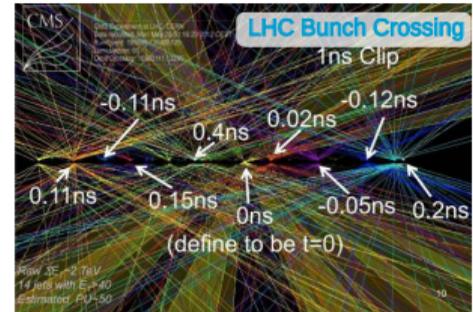
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## Example with timing info



added timing layer



# The need for new timing detectors

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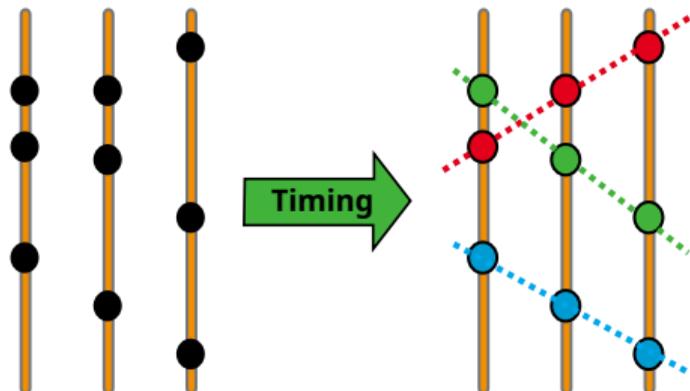
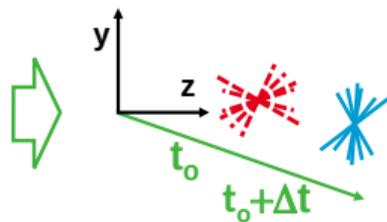
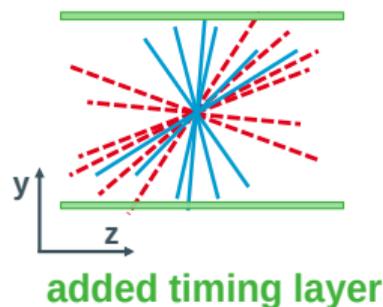
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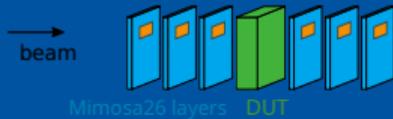
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## Example with timing info



# Test beam and telescopes



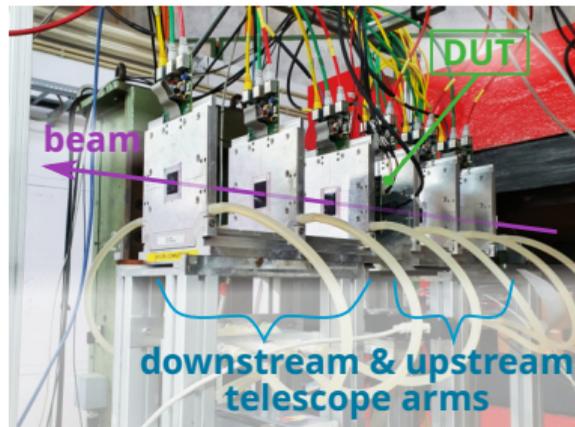
HEP detector R&D: dedicated beam tests for conceptual / technical design, calibrations, commissioning, ...  
→ DESY II Testbeam Facility



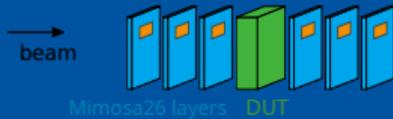
Integral part of test beam infrastructure: **Beam Telescopes**

→ EUDET-type telescopes: 6 layers of MIMOSA26 pixel sensors

- ▶ Monolithic Active Pixel Sensor
- ▶  $1152 \times 576$  pixels, pitch:  $18.4 \mu\text{m}$
- ▶ Measured intrinsic sensor resolution:  $\sigma \cong 3 \mu\text{m}$
- ▶ Rolling shutter readout, readout cycle  $115 \mu\text{s}$



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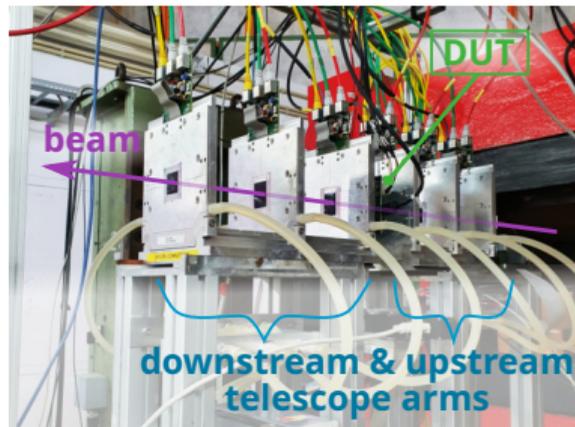


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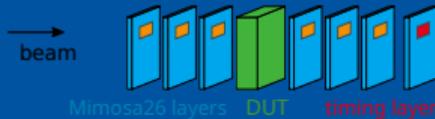
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“No“ time resolution → **upgrade needed**  
to meet requirements of future detector test campaigns

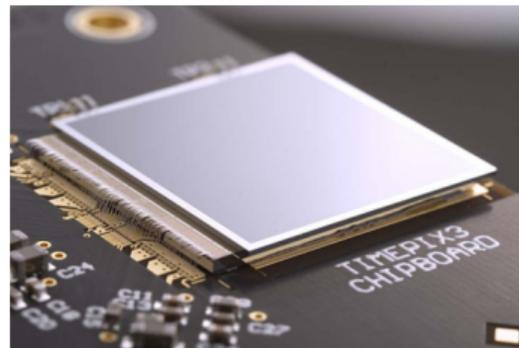


# Upgrade Plans

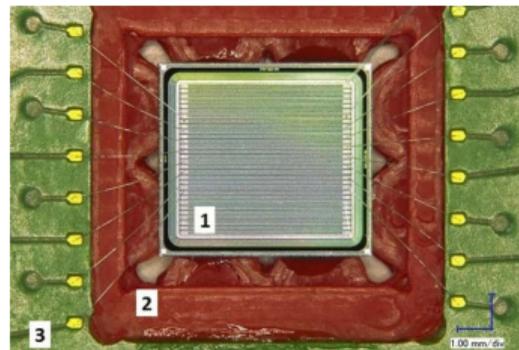


Add faster device for time stamping the tracks → timing layer

- ▶ Short term: existing sensor as intermediate solution
  - ▶ Timepix3
  - ▶ Already existing and functional
  - ▶ Timestamps  $\mathcal{O}(1 \text{ ns})$
- ▶ Long term: develop next-generation timing layer
  - ▶ LGAD → [this talk](#)
  - ▶ Allow for picosecond-timing
  - ▶ Requires R&D
  - ▶ Dedicated ROC? Start with Timepix3 for first prototypes



[CERN-PHOTO-201702-048-4]



[doi.org/10.1140/epja/s10050-020-00186-w]

# LGAD

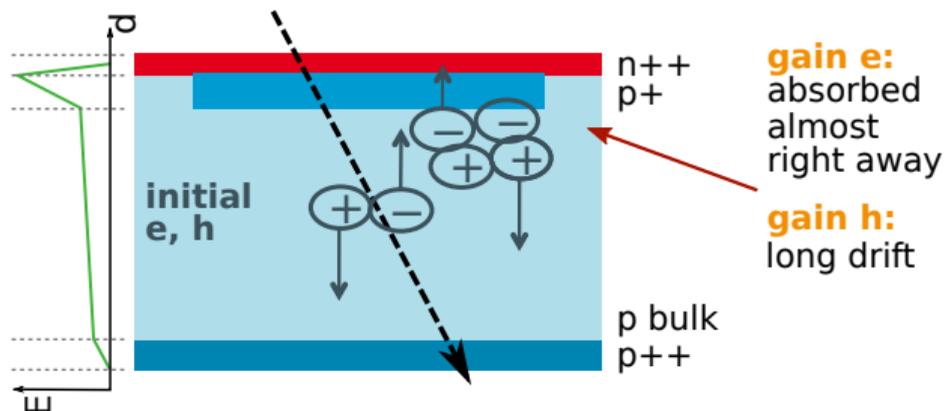
## Low Gain Avalanche Diodes

Ultra Fast Silicon Detectors  
optimised for timing measurements:

Thin multiplication layer

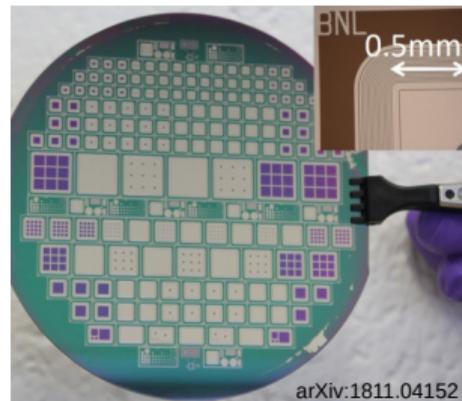
→ High field

→ Increase signal by factor  $\sim 10$



LGADs are routinely produced in various sizes and pad numbers  
(e.g. by CNM, FBK, HPK)

$\mathcal{O}(30 \text{ ps})$  time resolution possible



# LGADs for Timing

Time resolution is affected by:

- ▶ Each step in the read-out process
- ▶ Anything that changes the shape of the signal

$$\sigma_t^2 = \sigma_{\text{TimeWalk}}^2 + \sigma_{\text{LandauNoise}}^2 + \sigma_{\text{Distortion}}^2 + \sigma_{\text{Jitter}}^2 + \sigma_{\text{TDC}}^2$$

arXiv:1704.08666

# LGADs for Timing

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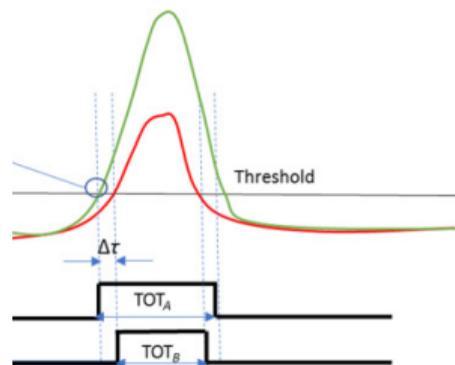
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Variation in time of arrival  
due to different signal amplitudes

Compensation:  
Constant Fraction Triggering  
or amplitude-based correction (TOT)



Time walk effect OE 56(3), 031224 (2017)

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Caused by inhomogenities in  
drift velocity & weighting field

Time-to-digital converter  
contribution  $\Delta T/\sqrt{12}$  (bin width)

Compensation:  
saturated drift velocity  
& optimised geometry ("parallel plate")

in most cases small contribution

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## Energy deposit

Current fluctuations due to signal shape variations for MIP ionization

## Time-Of-Arrival variations due to noise

- sensor noise
- electronics noise
- slew rates (dV/dt)

arXiv:1704.08666

= the main contributors → low gain, thin detectors (see next slides)

# Why Low Gain?

High gain has many drawbacks:  
risk of breakdown, power consumption, **higher noise**

“Excess Noise Factor“ (F): additional noise induced by the multiplication mechanism

(gain not constant  $\rightarrow$  additional fluctuations in current)

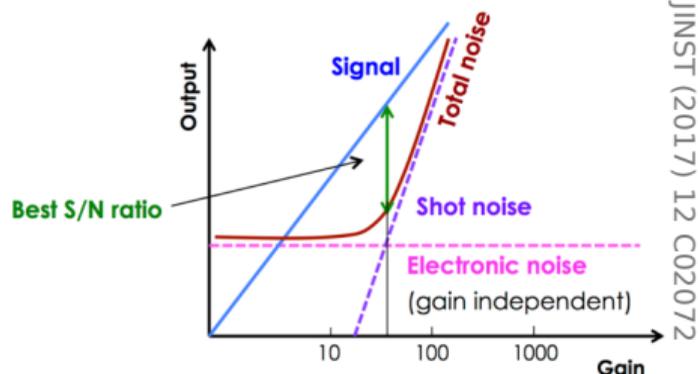
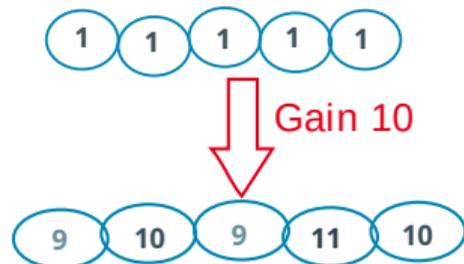
$$F \sim G^x$$

signal after multiplication: multiplied by  $G$

current noise increases with  $\sqrt{F}$

$\rightarrow$  S/N ratio deteriorates at higher gain

For a given ENF, there is an optimum gain (10  $\sim$  30)



# Why thin sensors?

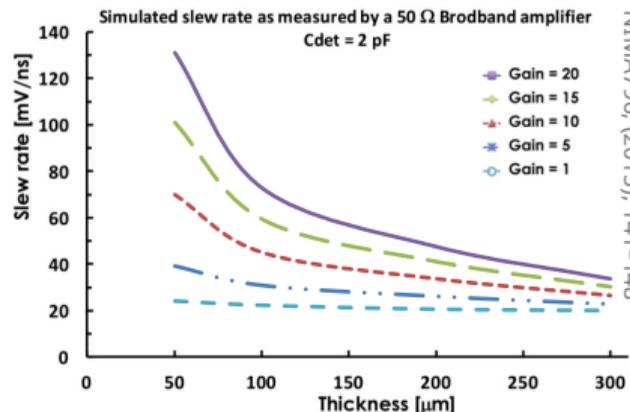
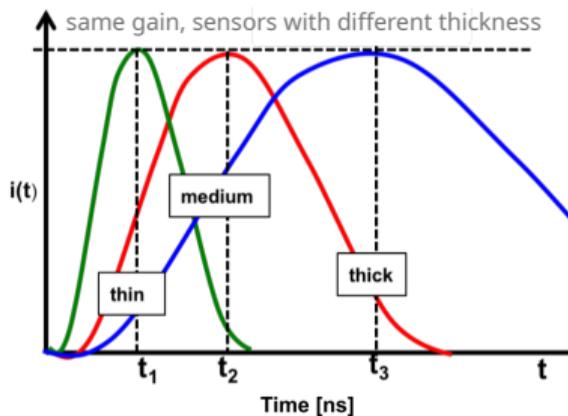
Current fluctuations are due to statistics of MIP ionization

- ▶ For a fixed gain: amplitude of the signal independent of thickness  $d$ :

$$I_{max} \sim n_{eh-initial} G q v_{sat}$$

arXiv:1704.08666

- ▶ Slew rate ( $dV/dt$ ): increases with  $\frac{G}{d}$



NIMA796, (2015), 141-148

→ Thin detectors improve time resolution (35-50  $\mu m$  available)

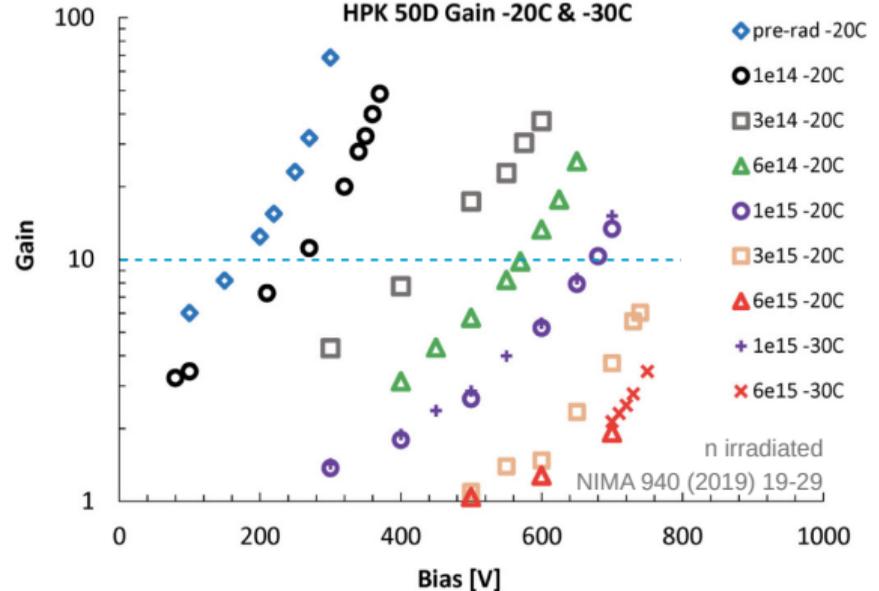
# R&D Challenge: Radiation Tolerance

Irradiation causes three main effects:

- ▶ Decreased charge collection efficiency
- ▶ Increased leakage current
- ▶ Change of doping profile

Deactivation of p-doping by Boron removal

→ Gain reduction due to irradiation



# R&D Challenge: Radiation Tolerance (2)

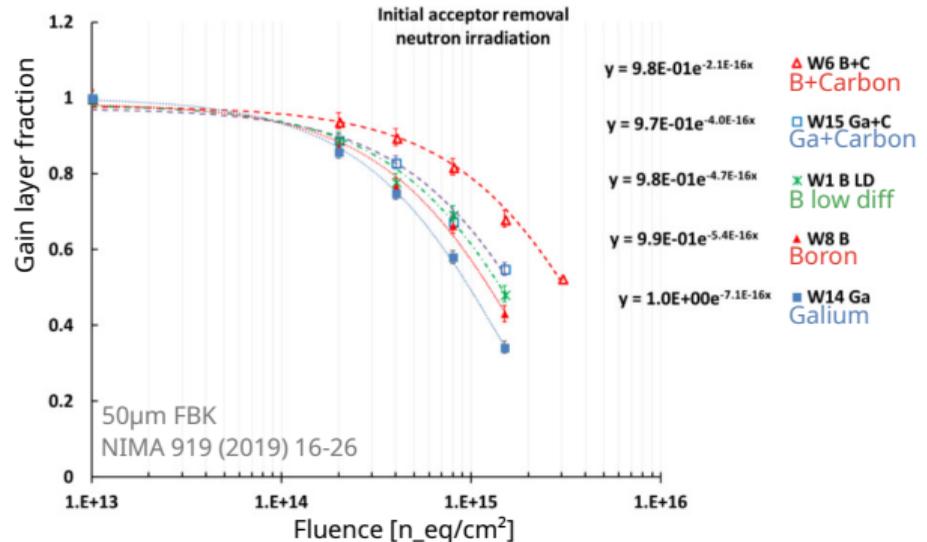
Lots of R&D ongoing, different doping profiles and ion implants:

Defect Engineering of the gain implant

- Carbon co-implantation in gain layer volume
- Boron as gain layer implant

Modification of gain layer profile

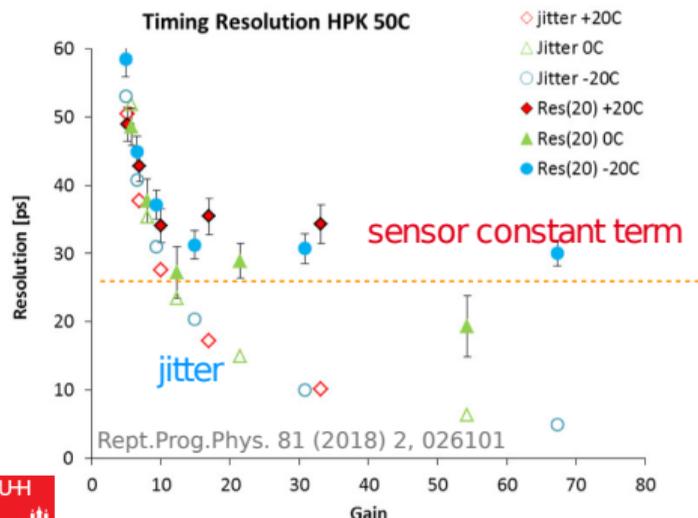
- Narrower doping layer with higher initial doping



# Ultra-fast silicon detectors - performance

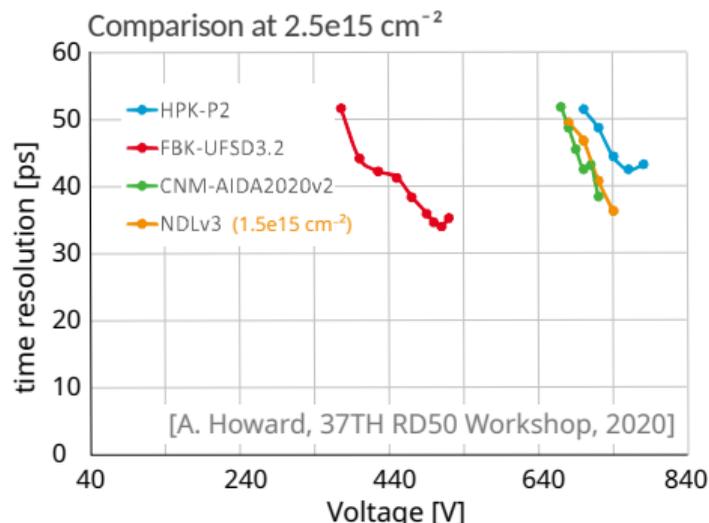
Example: UFSD from Hamamatsu

- LGAD with 50  $\mu\text{m}$  thickness
- Value of gain  $\sim 20$
- 30 ps time resolution



Example: Irradiation study for HGTD

- LGAD with 45 – 55  $\mu\text{m}$  thickness
- Different vendors/implantations
- $\sim 40$  ps time resolution after irradiation



# R&D Challenge: Fill Factor

Segmentation to improve spatial resolution

- ▶ Inter-pixel region:  
isolation and termination structures  
(p-stop, Junction Termination Extension, virtual GR)
- ▶ Carriers generated in this area not multiplied
- ▶ Interpad regions with no gain  $\mathcal{O}(\approx 30 \mu\text{m to } 70 \mu\text{m})$

→ R&D challenge:

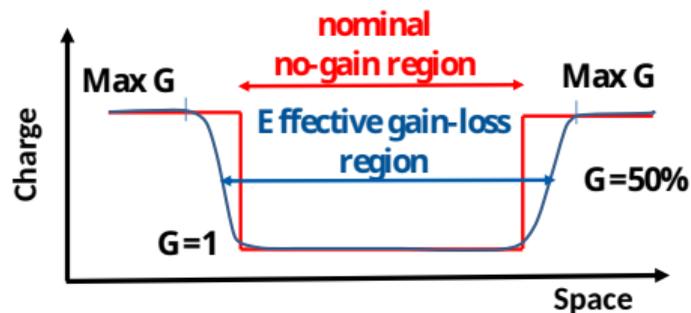
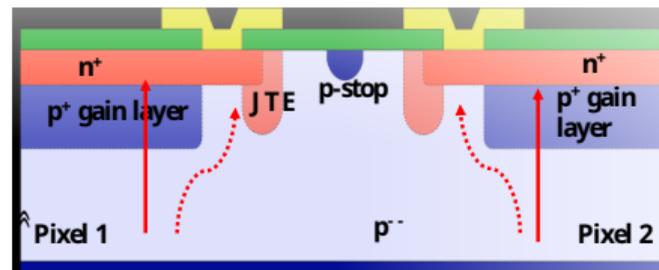
Segmentation with improved fill factor

Several technology options:

- ▶ Trench-isolated LGAD
- ▶ Inverse LGAD
- ▶ Resistive AC-Coupled LGAD

(see talk N. Cartiglia at last week's instrumentation seminar)

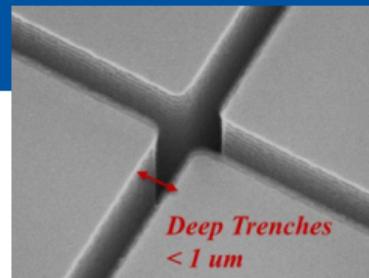
Standard segmentation



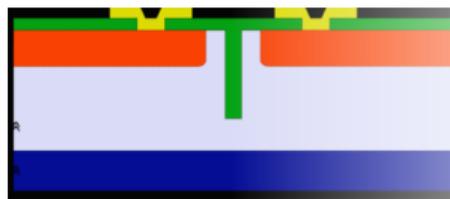
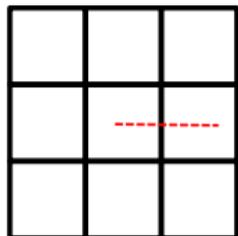
[G. Paternoster, 35th RD50 workshop, Nov 2019]

## Trench isolation:

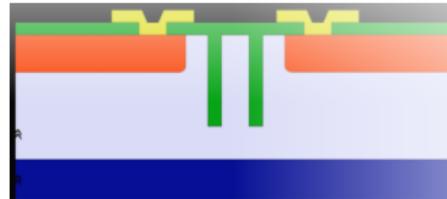
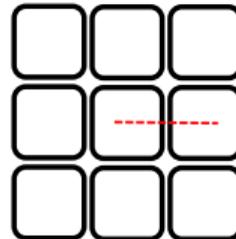
- ▶ JTE and p-stop replaced by trench to isolate the pixels
- ▶ Filled with Silicon Oxide
- ▶ Typical trench width  $< 1 \mu\text{m}$   
much smaller wrt. JTE and p-stop  
→ smaller no-gain region



## 1 Trench Layout (trench grid)



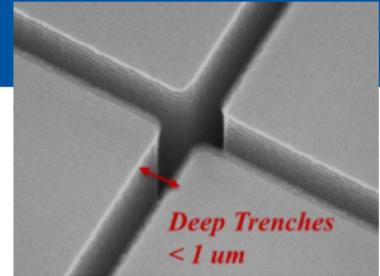
## 2 Trenches Layout



[G. Paternoster, 35th RD50 workshop, Nov 2019]

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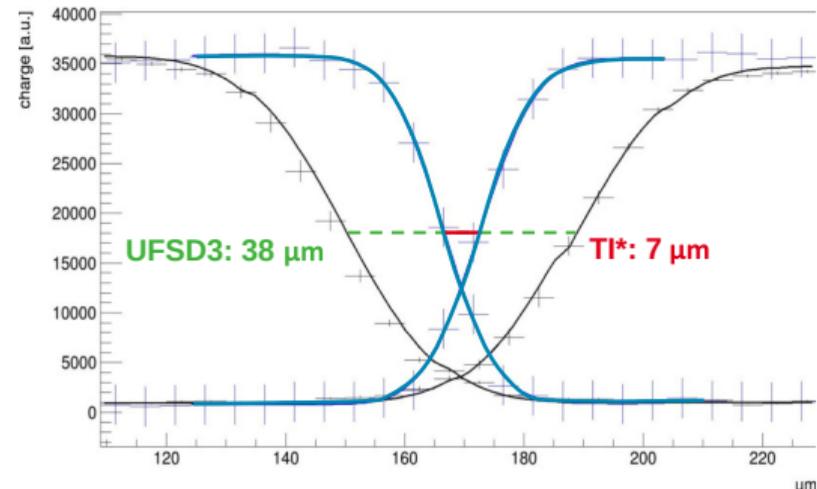


Layout	Nominal no-gain	Effective gain-loss
1 Trench	$\sim 4 \mu\text{m}$	$\sim 6 \mu\text{m}$
2 Trenches	$\sim 6 \mu\text{m}$	$\sim 3 \mu\text{m}$

[G. Paternoster, 35th RD50 workshop, Nov 2019]

Trade-off between minimizing gain-loss region and reducing E-field at the border

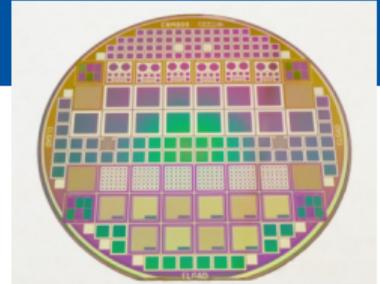
Comparison of FBK productions: UFSD3 vs Trench-Isolated



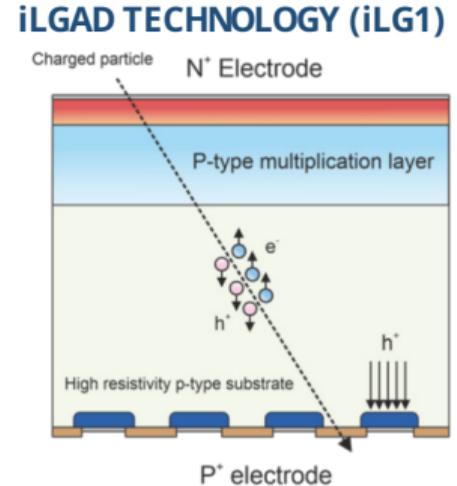
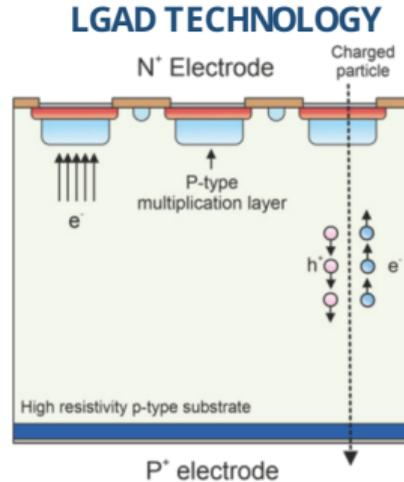
[F. Siviero, 35th RD50 workshop, Nov 2019]

## Inverse LGADs:

- ▶ No segmentation of the multiplication layer
- ▶ Hole collection
- ▶ Complex double side process (first generation)



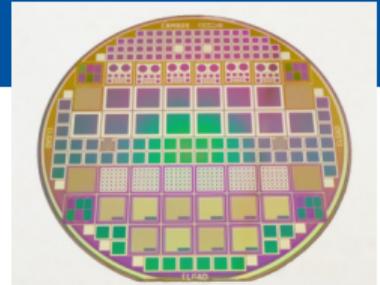
[D. Flores, SIMDET '16, Sep 2016]



[A. D. Moreno, 16 th Trento Workshop, Feb 2021]

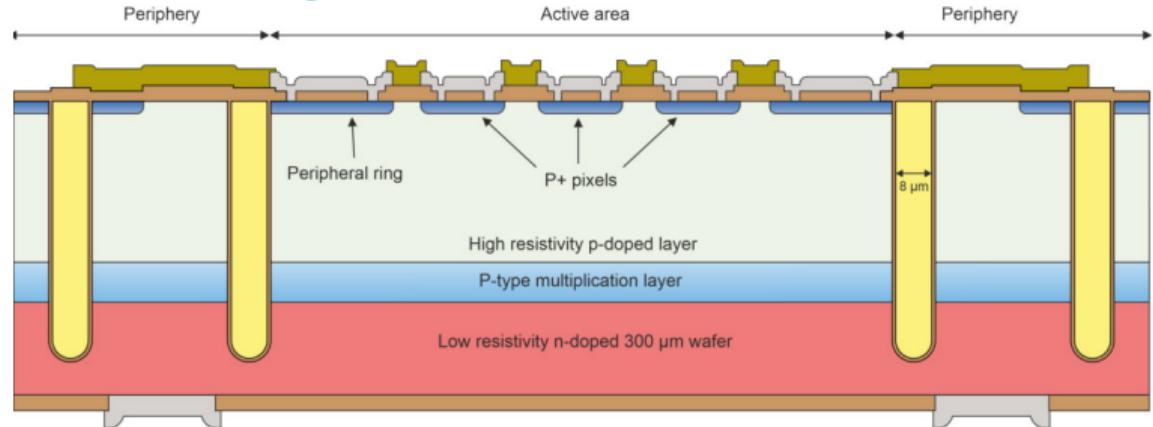
## Inverse LGADs:

- ▶ No segmentation of the multiplication layer
- ▶ Hole collection
- ▶ Trenches to isolate the active area (third generation)
- ▶ Single-side process



[D. Flores, SIMDET '16, Sep 2016]

### inverse LGAD (third generation)



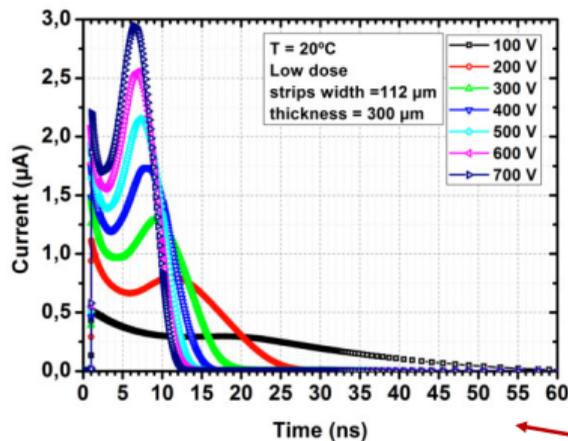
[A. D. Moreno, 16 th Trento Workshop, Feb 2021]

# iLGAD for Timing

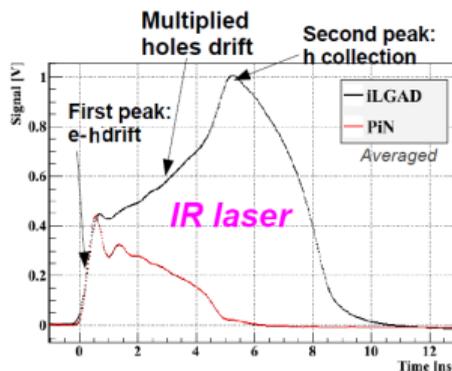
To use iLGADs for timing applications → Reduce the thickness of the detector  
CNM: fabrication with two different approaches

1. Epitaxial wafer + epitaxial multiplication
2. Si-Si wafers + implanted multiplication

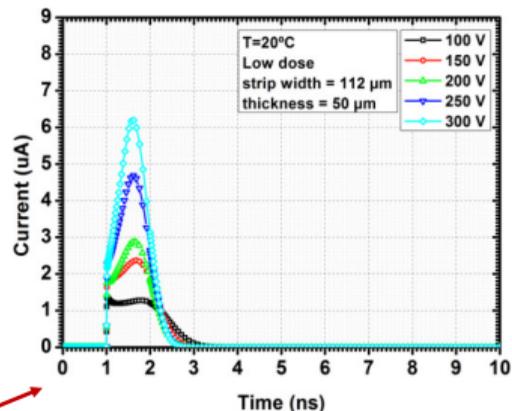
TCAD Simulation 300  $\mu\text{m}$  thick iLGAD



Experimental 300  $\mu\text{m}$  thick iLGAD



TCAD Simulation 50  $\mu\text{m}$  thick iLGAD



Different scale!

# Timing layer timeline

- ▶ Trench-isolated LGADs: part of RD50 run @ FBK  
Pixel pitch:  $55\ \mu\text{m} \times 55\ \mu\text{m}$ , number of pixels  $55 \times 55$   
Production to finish end of this month
- ▶ Inverse LGADs: part of RD50 run @ CNM  
Pixel pitch:  $55 \times 55\ \mu\text{m}^2$ , number of pixels  $256 \times 256$   
Mask design/fabrication ongoing,  
Production to be finished in September

Other ingredients for improved timing?  
Trigger Logic Unit, DAQ software  
→ **AIDA-2020 TLU, EUDAQ 2**



# Summary & Outlook

- ▶ Low Gain Avalanche Diodes to measure both time and space - with improved signal-to-noise ratio
- ▶ For timing: 30-50  $\mu\text{m}$  thickness, gain (O)(10)
- ▶ R&D ongoing on
  - ▶ radiation hardness (doping profile, ion implantats)
  - ▶ segmentation (Trench / Resistive AC / i-LGAD)
  - ▶ and more (uniformity, electronics, ...)
- ▶ More and more R&D on fast timing detectors  
→ growing need for timing layer to test them



→ **LGAD layer for beam telescopes**  
**for the next decade of successful testbeam operation**

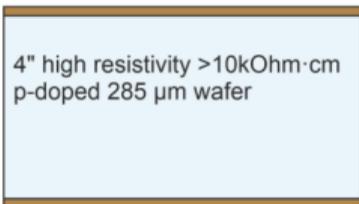
# Backup Slides

# iLGAD Third Generation (iLG3): Fabrication Process

We are planning to carry out this fabrication with two different approaches:

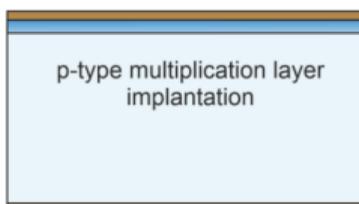
1. Epitaxial wafer + epitaxial multiplication
2. **Si-Si wafers + implanted multiplication**

(1)



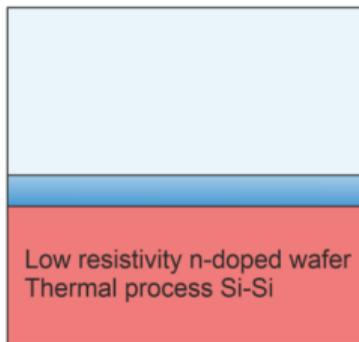
CNM

(2)



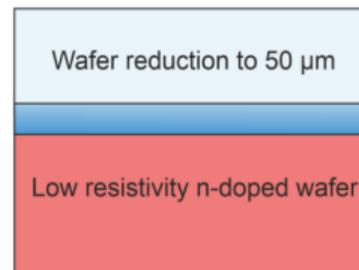
Dose/energy multiplication  
layer is adapted to the Si-Si  
thermal process

(3)



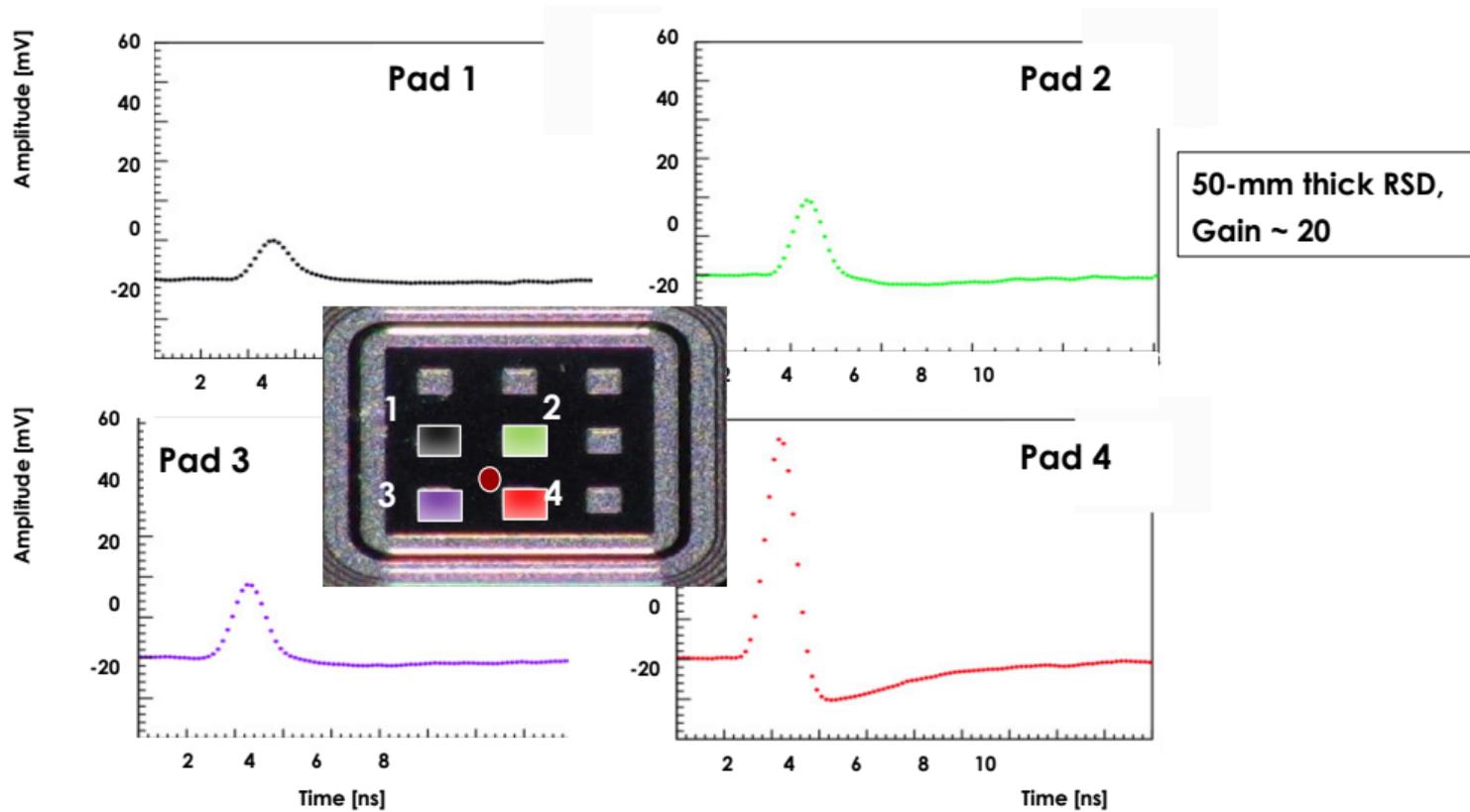
Foundry

(4)



After (4), the profile is the same  
as standard LGAD runs. This is the  
starting point for the fabrication.

# Example of signal sharing



The laser is shot at the position of the red dot: the signal is seen in 4 pads